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# EE C245 - ME C218 Introduction to MEMS Design Fall 2012

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**Lecture Module 10: Resonance Frequency**

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## Lecture Outline


- Reading: Senturia, Chpt. 10: §10.5, Chpt. 19
- Lecture Topics:
  - ↖ Estimating Resonance Frequency
  - ↖ Lumped Mass-Spring Approximation
  - ↖ ADXL-50 Resonance Frequency
  - ↖ Distributed Mass & Stiffness
  - ↖ Folded-Beam Resonator

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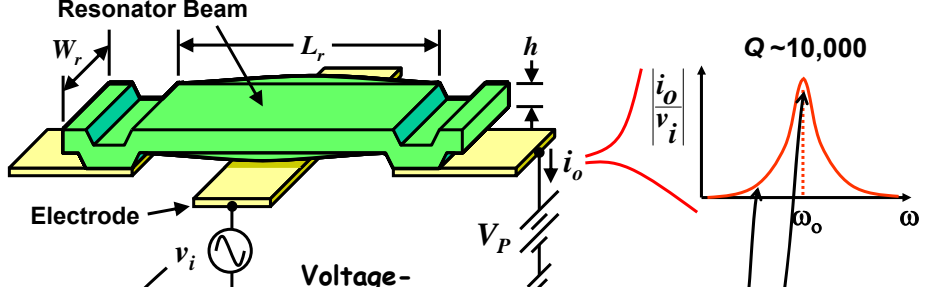


## Estimating Resonance Frequency

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## Clamped-Clamped Beam $\mu$ Resonator



$v_i = V_i \cos[\omega_o t] \rightarrow f_i = F_i \cos[\omega_o t]$

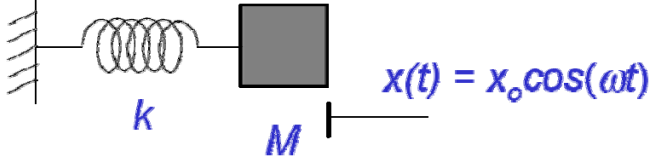
- $\omega \neq \omega_o$ : small amplitude
- $\omega = \omega_o$ : maximum amplitude  $\rightarrow$  beam reaches its maximum potential and kinetic energies

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**Estimating Resonance Frequency**

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- Assume simple harmonic motion:



$x(t) = x_o \cos(\omega t)$

- Potential Energy:

$$W(t) = \frac{1}{2} kx^2(t) = \frac{1}{2} kx_o^2 \cos^2(\omega t)$$

- Kinetic Energy:

$$K(t) = \frac{1}{2} M\dot{x}^2(t) = \frac{1}{2} Mx_o^2 \omega^2 \sin^2(\omega t)$$

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**Estimating Resonance Frequency (cont)**

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- Energy must be conserved:
  - Potential Energy + Kinetic Energy = Total Energy
  - Must be true at every point on the mechanical structure

Occurs at peak displacement      Occurs when the beam moves through zero displacement

Maximum Potential Energy      Maximum Kinetic Energy

Stiffness      Displacement Amplitude      Mass      Radian Frequency

$$W_{\max} = \frac{1}{2} kx_o^2 = K_{\max} = \frac{1}{2} M\omega^2 x_o^2$$

- Solving, we obtain for resonance frequency:

$$\omega = \sqrt{\frac{k}{M}}$$

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**Example: ADXL-50**

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- The proof mass of the ADXL-50 is many times larger than the effective mass of its suspension beams
  - Can ignore the mass of the suspension beams (which greatly simplifies the analysis)
- Suspension Beam:  $L = 260 \mu\text{m}$ ,  $h = 2.3 \mu\text{m}$ ,  $W = 2 \mu\text{m}$

Proof Mass  
Sense Finger  
Suspension Beam in Tension

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**Lumped Spring-Mass Approximation**

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- Mass is dominated by the proof mass
  - 60% of mass from sense fingers
  - Mass =  $M = 162 \text{ ng}$  (nano-grams)
- Suspension: four tensioned beams
  - Include both bending and stretching terms [A.P. Pisano, BSAC Inertial Sensor Short Courses, 1995-1998]

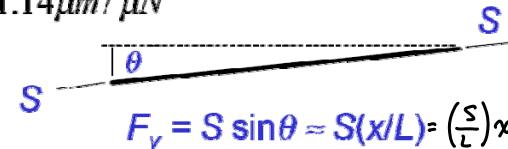
Bending compliance  $k_b^{-1}$   
Stretching compliance  $k_{st}^{-1}$

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## ADXL-50 Suspension Model


- Bending contribution:
 
$$k_b^{-1} = (1/k_c + 1/k_e) = 2 \left[ \frac{(L/2)^3}{3E(Wh^3/12)} \right] = \frac{L^3}{EWh^3} = 4.2 \mu\text{m} / \mu\text{N}$$
- Stretching contribution:
 
$$k_{st}^{-1} = L/S = \frac{L}{\sigma_y Wh} = 1.14 \mu\text{m} / \mu\text{N}$$



$F_y = S \sin \theta \approx S(x/L) = \underbrace{\left(\frac{S}{L}\right)}_{k_{st}} x$
- Total spring constant: *add bending to stretching*  
*(since they are in parallel)*

$$k = 4(k_b + k_{st}) = 4(0.24 + 0.88) = 4.5 \mu\text{N} / \mu\text{m}$$


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## ADXL-50 Resonance Frequency

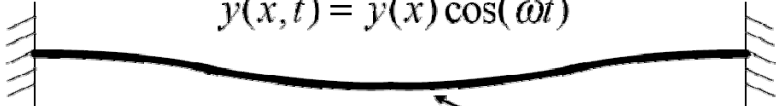
- Using a lumped mass-spring approximation:
 
$$f = \frac{1}{2\pi} \sqrt{\frac{k}{M}} = \frac{1}{2\pi} \sqrt{\frac{4.48 \text{ N/m}}{162 \times 10^{-12} \text{ kg}}} = 26.5 \text{ kHz}$$
- On the ADXL-50 Data Sheet:  $f_0 = 24 \text{ kHz}$ 
  - ↗ Why the 10% difference?
  - ↗ Well, it's approximate ... plus ...
  - ↗ Above analysis does not include the frequency-pulling effect of the DC bias voltage across the plate sense fingers and stationary sense fingers ... something we'll cover later on ...

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## Distributed Mechanical Structures

- Vibrating structure displacement function:
 

$$y(x, t) = \hat{y}(x) \cos(\omega t)$$



Maximum displacement function  
 (i.e., mode shape function)  
 Seen when velocity  $\dot{y}(x, t) = 0$
- Procedure for determining resonance frequency:
  - ↪ Use the static displacement of the structure as a trial function and find the strain energy  $W_{max}$  at the point of maximum displacement (e.g., when  $t=0, \pi/\omega, \dots$ )
  - ↪ Determine the maximum kinetic energy when the beam is at zero displacement (e.g., when it experiences its maximum velocity)
  - ↪ Equate energies and solve for frequency

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## Maximum Kinetic Energy

- Displacement:  $y(x, t) = \hat{y}(x) \cos[\omega t]$
- Velocity:  $v(x, t) = \frac{\partial y(x, t)}{\partial t} = -\omega \hat{y}(x) \sin[\omega t]$
- At times  $t = \pi/(2\omega), 3\pi/(2\omega), \dots$



Velocity topographical mapping

- ↪ The displacement of the structure is  $y(x, t) = 0$
- ↪ The velocity is maximum and all of the energy in the structure is kinetic (since  $W=0$ ):
 

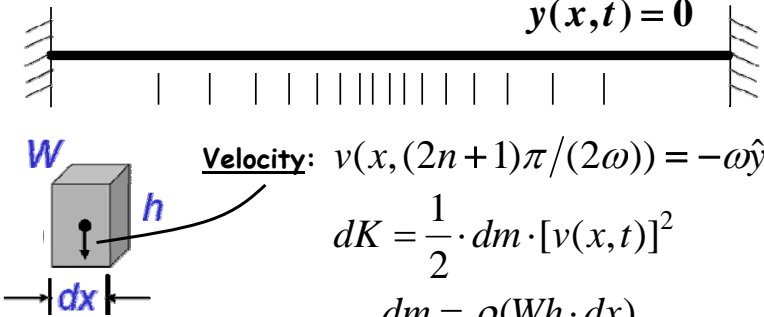
$$v(x, (2n + 1) \pi / (2\omega)) = -\omega \hat{y}(x)$$

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**Maximum Kinetic Energy (cont)**

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- At times  $t = \pi/(2\omega), 3\pi/(2\omega), \dots$



**Velocity:**  $v(x, (2n+1)\pi/(2\omega)) = -\omega \hat{y}(x)$

$$dK = \frac{1}{2} \cdot dm \cdot [v(x, t)]^2$$

$$dm = \rho(Wh \cdot dx)$$

- Maximum kinetic energy:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh dx v^2(x, t') = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx$$

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**The Raleigh-Ritz Method**

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- Equate the maximum potential and maximum kinetic energies:

$$K_{\max} = \int_0^L \frac{1}{2} \rho Wh \omega^2 \hat{y}^2(x) dx = \mathcal{W}_{\max}$$

- Rearranging yields for resonance frequency:

$$\omega = \sqrt{\frac{\mathcal{W}_{\max}}{\int_0^L \frac{1}{2} \rho Wh \hat{y}^2(x) dx}}$$

$\omega$  = resonance frequency  
 $\mathcal{W}_{\max}$  = maximum potential energy  
 $\rho$  = density of the structural material  
 $W$  = beam width  
 $h$  = beam thickness  
 $\hat{y}(x)$  = resonance mode shape

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**Example: Folded-Beam Resonator**

• Derive an expression for the resonance frequency of the folded-beam structure at left.

Use Rayleigh-Ritz method.

$$KE_{max} = PE_{max}$$

Kinetic Energy:

$$KE_{max} = \underbrace{KE_S}_{\text{shuttle}} + \underbrace{KE_t}_{\text{truss}} + \underbrace{KE_b}_{\text{beams}}$$

$$= \frac{1}{2} N_s^2 M_s + \frac{1}{2} N_t^2 M_t + \frac{1}{2} \int N_b^2 dM_b$$

mass of both trusses → Must integrate since the beam velocity is a function of location  $y$ !

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**Get Kinetic Energies**

Velocity of the shuttle:  $N_s = \omega_0 \Delta_0$   
 Resonance Freq. → Maximum Displacement Amplitude

$$\therefore KE_S = \frac{1}{2} N_s^2 M_s = \frac{1}{2} \omega_0^2 \Delta_0^2 M_s$$

Velocity of the truss:  $N_t = \frac{1}{2} N_s = \frac{1}{2} \omega_0 \Delta_0$

$$\therefore KE_t = \frac{1}{2} \left( \frac{1}{2} \omega_0 \Delta_0 \right)^2 M_t = \frac{1}{8} \omega_0^2 \Delta_0^2 M_t$$

Velocity of the beam segments:  
 ⇒ assume the mode shape is the same as the static displacement shape  
 ⇒ For segment AB:

$$\hat{x}(y) = \frac{F_x}{48 E I_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L \quad (1)$$

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### Folded-Beam Suspension

**Comb-Driven Folded Beam Actuator**

$$\hat{x}(y) = \frac{F_x}{48EI_z} (3Ly^2 - 2y^3) \quad 0 \leq y \leq L$$

Case:  $y=0 \quad \hat{x}(y=0) = 0 \quad \checkmark$

Case:  $y=L_c \quad \hat{x}(y=L_c) = \frac{F_x}{48EI_z} L^3 \rightarrow k = \frac{(F_x/L)}{x} = \frac{12EI_z}{L^3} = \frac{k_c}{2} \quad \checkmark$

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### Get Kinetic Energies (cont)

At  $y=L: x(L) = \frac{X_0}{2} = \frac{F_x L^3}{48EI_z}$

Substituting into (1):

$$\hat{x}(y) = \frac{X_0}{2} \left[ 3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]$$

Which yields the velocity:

$$v_b(y)|_{[AB]} = \frac{X_0}{2} \left[ 3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right] \omega_0$$

Plugging into the expression for  $KE_b$ :

$$KE_{[AB]} = \frac{1}{2} \int_0^L \frac{X_0^2 \omega_0^2}{4} \left[ 3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dM_{[AB]}$$

Static mass of beam [AB] =  $\frac{X_0^2 \omega_0^2 M_{[AB]}}{8L} \int_0^L \left[ 3\left(\frac{y}{L}\right)^2 - 2\left(\frac{y}{L}\right)^3 \right]^2 dy$

$$KE_{[AB]} = \frac{13}{280} X_0^2 \omega_0^2 M_{[AB]}$$

Anchor  $h = \text{thickness}$

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### Get Kinetic Energies (cont)

For segment CD:

$$v_b(y)|_{CD} = X_0 \left[ 1 - \frac{3}{2} \left( \frac{y}{L} \right)^2 + \left( \frac{y}{L} \right)^3 \right] \omega_0$$

Thus:

$$KE_{CD} = \frac{X_0^2 \omega_0^2 M_{CD}}{2L} \int_0^L \left[ 1 - \frac{3}{2} \left( \frac{y}{L} \right)^2 + \left( \frac{y}{L} \right)^3 \right]^2 dy$$

$KE_{CD} = \frac{83}{280} X_0^2 \omega_0^2 M_{CD}$  ← Static mass of beam [CD]

Let  $M_b \hat{=}$  total mass of the 8 beams.

Then:  $M_{AB} = M_{CD} = \frac{1}{8} M_b$

Thus:

$$KE_b = 4 KE_{AB} + 4 KE_{CD} = \frac{6}{35} X_0^2 \omega_0^2 M_b$$

and

$$KE_{max} = X_0^2 \omega_0^2 \left[ \frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right]$$

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### Get Potential Energy & Frequency

$PE_{max}$  is simply the work done to achieve maximum deflection:

$$PE_{max} = \frac{1}{2} k_x X_0^2 = k_c X_0^2$$

Thus, using Rayleigh-Ritz:

$$KE_{max} = PE_{max}$$

$$X_0^2 \omega_0^2 \left[ \frac{1}{2} M_s + \frac{1}{8} M_t + \frac{6}{35} M_b \right] = \frac{1}{2} k_x X_0^2 = k_c X_0^2$$

$$\omega_0 = \left[ \frac{k_x}{M_{eq}} \right]^{1/2} = k_c$$

where  $M_{eq} = M_s + \frac{1}{4} M_t + \frac{12}{35} M_b$

(Resonance Frequency of a Folded-Beam Suspended Shuttle)

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## Brute Force Methods for Resonance Frequency Determination

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## Basic Concept: Scaling Guitar Strings

**Guitar String**

Vib. Amplitude

Low Q

High Q

110 Hz

Freq.

Vibrating "A" String (110 Hz)

**Freq. Equation:**

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

Stiffness

Mass

Guitar

**μMechanical Resonator**

Metallized Electrode

$W_r$

$L_r$

Anchor

Polysilicon Clamped-Clamped Beam

$h_r$

[Bannon 1996]

Transmission [dB]

$f_o = 8.5\text{MHz}$

$Q_{vac} = 8,000$

$Q_{air} \sim 50$

**Performance:**

$L_r = 40.8\mu\text{m}$

$m_r \sim 10^{-13}\text{ kg}$

$W_r = 8\mu\text{m}, h_r = 2\mu\text{m}$

$d = 1000\text{\AA}, V_p = 5\text{V}$

Press. = 70mTorr

Frequency [MHz]

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### Anchor Losses

$Q = 300$  at 70MHz

**Problem:** direct anchoring to the substrate  $\Rightarrow$  anchor radiation into the substrate  $\Rightarrow$  lower  $Q$

$Q = 15,000$  at 92MHz

**Solution:** support at motionless nodal points  $\Rightarrow$  isolate resonator from anchors  $\Rightarrow$  less energy loss  $\Rightarrow$  higher  $Q$

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### 92 MHz Free-Free Beam $\mu$ Resonator

• Free-free beam  $\mu$ mechanical resonator with non-intrusive supports  $\Rightarrow$  reduce anchor dissipation  $\Rightarrow$  higher  $Q$

**Design/Performance:**  
 $L_f = 13.1 \mu\text{m}$ ,  $W_f = 6 \mu\text{m}$   
 $h = 2 \mu\text{m}$ ,  $d = 1000 \text{ \AA}$   
 $V_p = 28-76 \text{ V}$ ,  $W_g = 2.8 \mu\text{m}$   
 $f_0 = 92.25 \text{ MHz}$   
 $Q \sim 7,450$  @ 10mTorr

[Wang, Yu, Nguyen 1998]      EE C245: Introduction to MEMS Design      LecM 10      C. Nguyen      11/4/08      24

**Higher Order Modes for Higher Freq.**

**2nd Mode Free-Free Beam**

**3rd Mode Free Free Beam**

Distinct Mode Shapes

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**Flexural-Mode Beam Wave Equation**

• Derive the wave equation for transverse vibration:  
 Dynamic Equilibrium Condition for forces in the y-direction:  $F - (F + \frac{\partial F}{\partial x} dx) - \rho A dx \frac{\partial^2 u}{\partial t^2} = 0$  (1) *neglect the  $\frac{\partial F}{\partial x} dx$  term*

and the moment equilibrium condition:  $-F dx + \frac{\partial M}{\partial x} dx \approx 0$  (2)

Combining (1) & (2):

$$\frac{\partial^2 M}{\partial x^2} dx = -\rho A dx \frac{\partial^2 u}{\partial t^2} \rightarrow \frac{\partial^2}{\partial x^2} \left( -EI \frac{\partial^2 u}{\partial x^2} \right) = -\rho A \frac{\partial^2 u}{\partial t^2} \rightarrow \frac{\partial^2 u}{\partial t^2} = \left( \frac{EI}{\rho A} \right) \frac{\partial^4 u}{\partial x^4}$$

$$I_y = \frac{Wh^3}{12}$$

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**Example: Free-Free Beam**

- Determine the resonance frequency of the beam
- Specify the lumped parameter mechanical equivalent circuit
- Transform to a lumped parameter electrical equivalent circuit
- Start with the flexural-mode beam equation:

$$\frac{\partial^2 u}{\partial t^2} = \left( \frac{EI}{\rho A} \right) \frac{\partial^4 u}{\partial x^4}$$

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**Free-Free Beam Frequency**

- Substitute  $u = u_1 e^{j\omega t}$  into the wave equation:

$$\frac{\partial^4 u}{\partial x^4} = \left( \omega^2 \frac{\rho A}{EI} \right) u \quad (1)$$

- This is a 4<sup>th</sup> order differential equation with solution:

$$u(x) = A \cosh kx + B \sinh kx + C \cos kx + D \sin kx \quad (2)$$

*Give the mode shape during resonance vibration.*

- Boundary Conditions:

At $x = 0$	At $x = l$	
$\frac{\partial^2 u}{\partial x^2} = 0$	$\frac{\partial^2 u}{\partial x^2} = 0$	$M = 0$ (Bending moment)
$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial^3 u}{\partial x^3} = 0$	$\frac{\partial M}{\partial x} = 0$ (Shearing force)

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**Free-Free Beam Frequency (cont)**

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- Applying B.C.'s, get  $A=C$  and  $B=D$ , and
 
$$\begin{bmatrix} (\cosh kl - \cos kl) & (\sinh kl - \sin kl) \\ (\sinh kl + \sin kl) & (\cosh kl - \cos kl) \end{bmatrix} \begin{bmatrix} A \\ B \end{bmatrix} = 0 \quad (3)$$
- Setting the determinant = 0 yields
 
$$\cos kl = \frac{1}{\cosh kl}$$
- Which has roots at
 
$$k_1 l = 4.730 \quad k_2 l = 7.853 \quad k_3 l = 10.996$$
- Substituting (2) into (1) finally yields:
 
$$k^4 = \frac{\rho A}{EI} \omega^2 \rightarrow f_n = \frac{(k_n l)^2}{2\pi l^2} \sqrt{\frac{EI}{\rho A}}$$

These values of  $k_n l$  correspond to the different modes of vibration!

Free-Free Beam Frequency Equation


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**Higher Order Free-Free Beam Modes**

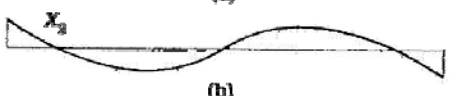
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Mode	$n$	Nodal Points	$k_n l$	$f_n/f_1$
Fundamental ( $f_1$ )	1	2	4.730	1.000
1st Harmonic	2	3	7.853	2.757
2nd Harmonic	3	4	10.996	5.404
3rd Harmonic	4	5	14.137	8.932
4th Harmonic	5	6	17.279	13.344


← More than 10x increase



Fundamental Mode (n=1)




1st Harmonic (n=2)



2nd Harmonic (n=3)

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## Mode Shape Expression


- The mode shape expression can be obtained by using the fact that  $A=C$  and  $B=D$  into (2), yielding

$$u_x = \mathcal{A} \left[ \left( \frac{\mathcal{A}}{\mathcal{B}} \right) (\cosh kx + \cos kx) + (\sinh kx + \sin kx) \right]$$

- Get the amplitude ratio by expanding (3) [the matrix] and solving, which yields

$$\frac{\mathcal{A}}{\mathcal{B}} = \frac{\sin kl - \sinh kl}{\cosh kl - \cos kl}$$

- Then just substitute the roots for each mode to get the expression for mode shape



Fundamental Mode (n=1)  
 [Substitute  $k_1 l = 4.730$ ]

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31